Charge questions:

•What are the important differences in the final structure in relation to the observed properties?

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•What Changes need to be made?

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•What new things should be tried?

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- Goals: Better, Faster, Cheaper (Pick 2?) Make it routine, low cost (less important)
 - Can we mechanically polish, do a light chemical polish and be done? (Reece)
 - What should that process be? (Mechanical, CBP [30-40 micron removal], EP[low T], 120 bake)
 - Low T harder on multicells
 - Optimal T still unknown
 - What roughness (as a function of scale) is good enough?
 - Non HF-based processes to achieve ~15 microns

- Can point repair close cavity performance distributions and reduce initial processing? (Ge)
 - Laser Re-melting: Purity, Surface Roughness (scale)
 - Vortex Removal (Gigi, Alex G.)
 - Flaw Detection (Beardon) Speed vs Resolution (roughness question above)
 - Faster automated inspection systems
 - Build library of flaws
 - In fabrication process

- New surface treatments and Films
 - Plasma Treatments (Upadhyay) (Dry vs Wet?)
 - Layered Superconductor Growth (Proslier)

•What are the important differences in the final structure in relation to the observed properties?

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- •What Changes need to be made?
 - Control
 - Press for standards
- •What new things should be tried?
 - Understand the underlying physics/engineering of mechanical polishing, and all other processes
 - •What state of the surface is really necessary